Ring Opening Metathesis Polymerization for 157 nm Photoresists

<u>Brian Osborn</u> September 11, 2001



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Ring Opening Metathesis Polymerization (ROMP)

Advantages

- Low catalyst loading (< 50 ppm), therefore little residual metal (Ru)
- Polymerizes geminally disubstituted norbornenes
- Robust catalyst, functional group and water tolerant
- Molecular weight can be controlled



Geminally Disubstituted Norbornenes

ROMP catalysts easily polymerize key monomers:





• The 193 nm System Approach

Incorporation of dinorbornene and carboxylic acid (-COOH) in the polymer composition increases the polymer's T_g

• One problem, however:

Dissolution rate increases rapidly with acid loading

• The 157 nm solution:

Use dissolution inhibitors to slow dissolution rate of the base polymer and also alleviate swelling¹

¹Ito, H.; Allen, R. D.; Opitz, J.; Wallow, T. I; Truong, H. D.; Hofer, D. C.; Varanasi, P. R.; Jordhamo, G. M.; Jayaraman, S.; Vicari, R.; *Proc. SPIE* **2000**, *3999*, 2.



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193 nm System - Tsutomu Shimokawa, Kyle Patterson, et al.



TriCycloNonene (TCN) Copolymers





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New comonomers:

Exploration of new norbornene monomers with increased steric bulk to make hydrogenated polymer backbone less flexible.



Initial Synthesis Successful

<u>DiN</u>orbornene <u>H</u>exa<u>F</u>luoroisopropyl <u>A</u>lcohol (DNHFA)

- T_g is 85-90 °C after hydrogenation
- Abs. @ 157 nm: 3.3 µm⁻¹ (first pass)
- Absorbance is higher than expected – Polymer requires improved purification



F₃C²

HC

CF₃

New Dinorbornene ROMP Polymers











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ROMP Summary

- Dinorbornene copolymers look promising
- First TCN ROMP copolymers are completed

Future Work

- Fully characterize new polymers
- Continue ROMP copolymer synthesis
- Initial imaging experiments



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Metal Catalyzed Vinyl Addition Polymerization for 157 nm Photoresists

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Metal (Pd⁺²) Catalyzed Vinyl Addition Polymerization – 3F-TCN Platform



Synthesis of 5F-TCN Monomer



Higher fluorine content lends *lower* absorbance at 157 nm ...but lower yields.



Initial 3F-TCN-co-NBHFA Images





No dissolution inhibitor. Dissolution inhibitor added.

3F-TCN copolymer images have very poor contrast, until **dissolution inhibitor (DI)** added.



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3F-TCN-*co***-NBHFA** - *Binary Mask* A 70:30 blend of polymer and dissolution inhibitor.





BPO-R-007-A 70:30 polymer:DI blend 6% TPS-Nf, 0.3% TBAH 148.9 nm poly on 81.9 nm G0 0.7 σ aperture, binary mask PAB: 140 °C/60 s, PEB: 130 °C/90 s 60 s development in 0.26 N TMAH DOSE: 19.0 mJ/cm² FOCUS: 0.0 nm



3F-TCN-co-NBHFA - Phase Shift

120 nm 1:1.5 114nm FA#01083006 W#7050103-24 C5R0 .10um 1:3 LM-4700-1 5.0kV 2.7mm x150k SE(U) 9/4/2001 100 nm 1:3 121nm FA#01083006 W#7050103-24 C5R0 .12um 1:1.5 M-4700-1 5.0kV 2.7mm x150k SE(U) 9/4/2001



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Changing mask to a **strong phase shift** mask results in superior feature profiles, and smaller resolution possible.



BPO-R-009-A 70:30 polymer:DI blend 6% TPS-Nf, 0.3% TBAH 145.6 nm poly on 82.4 nm G0 0.3 σ aperture, phase shift mask PAB: 140 °C/60 s, PEB: 130 °C/90 s 20 s development in 0.26 N TMAH DOSE: 39.0 mJ/cm² FOCUS: 0.0 nm

3F-TCN-co-NBHFA - Phase Shift



FA#01083006 W#7050105-02 C5R7 .08um 1:3

LM-4700-1 5.0kV 2.5mm x150k SE(U) 9/4/200

FA#01083006 W#7050103-24 C5R0 .08um 1:3

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DOSE: 39.0 mJ/cm² FOCUS: 0.0 nm

Transparency Improvements to TCN Platform





Base polymer

Dissolution inhibitor

And, 6% TPS-Nf (PAG) 0.3% TBAH (base) for total formulation



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Base polymer absorbance @ 157 nm: 2.0 μm⁻¹

Formulated resist absorbance @ 157 nm: 2.7 μm⁻¹

Dissolution inhibitor has **strong impact on absorbance**!

Transparency Improvements to TCN Platform

Polymer absorbance is relatively low, therefore better imaging requires use of new, **more transparent dissolution inhibitors**



Improvement in Transparency of Resist Formulated with Dissolution Inhibitors



Conclusions and Future Work

- 3F-TCN-*co*-NBHFA platform shows very promising resolution in preliminary imaging studies,
- A limiting factor is the need to use more transparent dissolution inhibitors.
- Dissolution inhibitor strongly impacts image profile because of both improved contrast and changes in absorbance
- Recreate high yielding 5F-TCN monomer synthesis ...does this mean a trip to California??
- Start imaging work on 5F-TCN-*co*-NBHFA copolymer
- Evaluate more transparent dissolution inhibitors



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